

RECEIVED  
CENTRAL FAX CENTER

APR 28 2004

OFFICIAL

003

00862.022239

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**In re Application of:**

Shigeyuki UZAWA et al.

Application No.: 09/864,309

Filed: May 25, 2001

**For: EXPOSURE APPARATUS, COATING/  
DEVELOPING SYSTEM, DEVICE  
MANUFACTURING SYSTEM, DEVICE  
MANUFACTURING METHOD,  
SEMICONDUCTOR MANUFACTURING  
FACTORY, AND EXPOSURE APPARATUS  
MAINTENANCE METHOD**

Examiner: R. A. Jarrett

Group Art Unit: 2125

Confirmation No.: 2803

February 5, 2004

**Mail Stop RCE**  
**Commissioner for Patents**  
**P.O. Box 1450**  
**Alexandria, VA 22313-1450**

## INFORMATION DISCLOSURE STATEMENT

**Sir:**


In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed PTO-1449 form. Copies of these documents are also enclosed.

Applicants request that the above information be considered by the Examiner and that a copy of the enclosed PTO-1449 form be initialed and returned indicating that such information has been considered.

No fee is believed to be due with the filing of this paper. Nevertheless, the Commissioner is authorized to charge Deposit Account No. 06-1205 should any fee be deemed necessary for filing this paper.

Applicants' undersigned attorney may be reached in our Washington D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

  
Attorney for Applicants  
Steven E. Warner  
Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO  
30 Rockefeller Plaza  
New York, New York 10112-3801  
Facsimile: (212) 218-2200

SEW/eab

